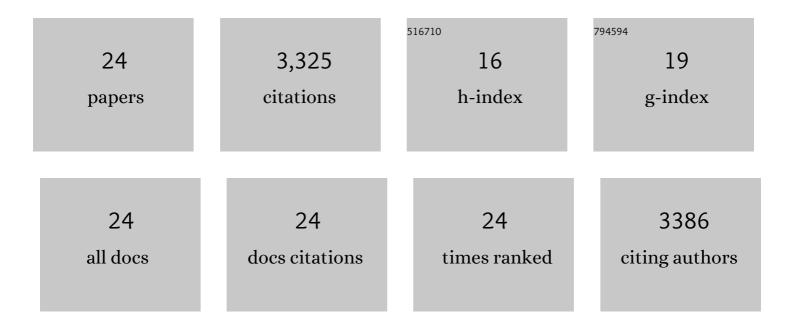
## Matthew A Hopcroft

List of Publications by Year in descending order

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#	Article	IF	CITATIONS
1	What is the Young's Modulus of Silicon?. Journal of Microelectromechanical Systems, 2010, 19, 229-238.	2.5	1,762
2	Temperature Dependence of Quality Factor in MEMS Resonators. Journal of Microelectromechanical Systems, 2008, 17, 755-766.	2.5	208
3	Temperature-Insensitive Composite Micromechanical Resonators. Journal of Microelectromechanical Systems, 2009, 18, 1409-1419.	2.5	202
4	Long-Term and Accelerated Life Testing of a Novel Single-Wafer Vacuum Encapsulation for MEMS Resonators. Journal of Microelectromechanical Systems, 2006, 15, 1446-1456.	2.5	183
5	Temperature-compensated aluminum nitride lamb wave resonators. IEEE Transactions on Ultrasonics, Ferroelectrics, and Frequency Control, 2010, 57, 524-532.	3.0	156
6	Frequency stability of wafer-scale film encapsulated silicon based MEMS resonators. Sensors and Actuators A: Physical, 2007, 136, 125-131.	4.1	114
7	Temperature-compensated high-stability silicon resonators. Applied Physics Letters, 2007, 90, 244107.	3.3	109
8	Thermally compensated aluminum nitride Lamb wave resonators for high temperature applications. Applied Physics Letters, 2010, 97, .	3.3	103
9	AlN thin films grown on epitaxial 3C–SiC (100) for piezoelectric resonant devices. Applied Physics Letters, 2010, 97, 141907.	3.3	73
10	Thermal Isolation of Encapsulated MEMS Resonators. Journal of Microelectromechanical Systems, 2008, 17, 175-184.	2.5	67
11	Optimal drive condition for nonlinearity reduction in electrostatic microresonators. Applied Physics Letters, 2006, 89, 214105.	3.3	60
12	Scaling of amplitude-frequency-dependence nonlinearities in electrostatically transduced microresonators. Journal of Applied Physics, 2007, 102, .	2.5	52
13	A study of electrostatic force nonlinearities in resonant microstructures. Applied Physics Letters, 2008, 92, .	3.3	45
14	Model and Observations of Dielectric Charge in Thermally Oxidized Silicon Resonators. Journal of Microelectromechanical Systems, 2010, 19, 162-174.	2.5	37
15	Composite flexural-mode resonator with controllable turnover temperature. , 2007, , .		33
16	Nonlinear Characterization of Electrostatic MEMS Resonators. , 2006, , .		27
17	Hermeticity and diffusion investigation in polysilicon film encapsulation for microelectromechanical systems. Journal of Applied Physics, 2009, 105, .	2.5	25
18	Multifunctional Integrated Sensors for Multiparameter Monitoring Applications. Journal of Microelectromechanical Systems, 2015, 24, 810-821.	2.5	25

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#	Article	IF	CITATIONS
19	Si-SiO2 Composite MEMS Resonators in CMOS Compatible Wafer-scale Thin-Film Encapsulation. , 2007, , $\cdot$		15
20	Electrostatic Tuning to Achieve Higher Stability Microelectromechanical Composite Resonators. Journal of Microelectromechanical Systems, 2011, 20, 1355-1365.	2.5	13
21	Acceleration sensitivity in beam-type electrostatic microresonators. Applied Physics Letters, 2007, 90, 014103.	3.3	8
22	Influence of the temperature dependent nonlinearities on the performance of micromechanical resonators. Applied Physics Letters, 2011, 99, .	3.3	7
23	Influence of the temperature dependent A-f effect on the design and performance of oscillators. , 2010, , .		1
24	Investigation of Orientation Dependence of the Thermal Expansion Coefficient in Silicon MEMS Resonators. , 2018, , .		0